

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:

Nobuo SHIMAZU et al.

Serial No. 09/765,388

Filed: January 22, 2001

For: ELECTRON BEAM PROXIMITY  
EXPOSURE APPARATUS AND  
METHOD



) **RESPONSE UNDER 37 CFR 1.116**

) **EXPEDITED PROCEDURE**

) Art Unit: 2881

) Examiner: D. Vanore

) Date: November 19, 2003

) Confirmation No.: 1026

**CERTIFICATE OF MAILING OR TRANSMISSION**

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K.M. McManus

**AMENDMENT AFTER FINAL**

Mail Stop AF  
Commissioner for Patents  
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Sir:

The following is presented in response to the Office Action mailed July 3, 2003, in connection with the above-identified application.